

IAP3 Rec'd PCTIPTO 23 DEC 2005

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: Kenji WATANABE et al.

Group Art Unit:

Serial Number: 10/543,151

Examiner:

Filed: July 25, 2005

For:

Confirmation Number:

MAPPING-PROJECTION-TYPE ELECTRON BEAM APPARATUS FOR

INSPECTING SAMPLE BY USING ELECTRONS EMITTED FROM THE

SAMPLE

Attorney Docket Number: Customer Number: 052886 38834

INFORMATION DISCLOSURE STATEMENT UNDER 37 C.F.R. §1.97(b)

Commissioner for Patents P. O. Box 1450 Alexandria, VA 22313-1450 December 23, 2005

Sir:

In compliance with 37 C.F.R. §1.56, Applicants direct the attention of the Patent and Trademark Office to the documents listed on the attached PTO/SB/08. This paper is being filed within the time periods set forth in 37 C.F.R. §1.97(b). A copy of each non-U.S. document is enclosed herewith.

The inventor considers Japanese Laid-open No. Hei 4-242060 to disclose a reflection election microscope having a similar electron beam deflection device.

If there are any fees due in connection with the filing of this paper, please charge Deposit Account No. 50-2866.

Respectfully submitted,

Westerman, Hattori, Danyelé & Adrian, LLP

plen G.Adrian Attorney for Applicants Registration No. 32,878 Telephone: (202) 822-1100

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SGA/arf Enclosures:

PTO/SB/08 3 Documents

Combined Form PTO/SB/08A&B	Complete if Known		
DE	Application Number	10/543,151	
INFORMATION DISCLOSURE	Confirmation Number		
STATEMENT BY APPLICANT	Filing Date	July 25, 2005. 04-18	
(use as many sheets as necessary)	First Named Inventor	Kenji WATANABE et a	
(use as many sheets as necessary)	Art Unit	2881	
- A	Examiner Name	K. Nguyen	
Sheet 1 of 1	Attorney Docket Number	052886	

U.S. PATENT DOCUMENTS						
Examiner Initials*	Cite	Document Number		Publication Date		
	No.1	Number	Kind Code ² (if known)	MM-DD-YYYY	Name of Patentee or Applicant of Cited Documer	
	1	US 5,576,833		11/19/1996	Miyoshi et al.	
		US				
		US				
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Examiner	Examiner Cite Foreign Patent Document	Publication Date	Name of Patentee or	Translation ⁶			
Initials*	No.1	Country Code ³	Number ⁴	Kind Code ⁵ (if known)		Applicant of Cited Document	r ranslation
	2	JP	4-242060		08/28/1992		
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NON PATENT LITERATURE DOCUMENTS			
Examiner Cite Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city, and/or country where published.			
	3	K. Tsuno, "Simulation of a Wien filter as beam separator in a low energy electron microscope", pp. 127-140, Ultramicroscopy 55 (1994).	
	-		

Examiner Signature	/Kiet Tuan Nguyen/	Date Considered	08/17/2008
		C with MDED 600	Design line through citation if not in

conformance and not considered. Include copy of this form with next communication to applicant.

English language Translation is attached.

Applicant's unique citation designation number (optional). See Kind Codes of USPTO Patent Documents at www.uspto.gov, MPEP 901.04 or in the comment box of this document. Tenter Office that issued the document, by the two-letter code (WIPO Standard ST. 3). For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the scrial number of the patent document. Xind of document by the appropriate symbols as indicated on the document under WIPO Standard ST. 16 if possible. Applicant is to indicate here if